IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of John J. Sidorowich Application No.: NEW Filed: HEREWITH For: METHOD AND APPARATUS FOR MULTIDOMAIN DATA ANALYSIS	Group Art Unit: Unknown Examiner: Unknown **INFORMATION DISCLOSURE STATEMENT** 121 Spear Street, Suite 290 San Francisco, CA 94105 (415) 512-1312

M/S PATENT APPLICATION
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicant(s) submit(s) herewith patents, publications or other information [attached hereto and listed on the attached Form PTO-1449 (modified)] of which he is aware, which he believe(s) may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

This Information Disclosure Statement:

(a) ☒ accompanies the new patent application submitted herewith. 37 CFR § 1.97(a).

(b) ☐ is filed within three months after the filing date of the application or within three months after the date of entry of the national stage of a PCT application as set forth in 37 CFR § 1.491.

(c) ☐ as far as is known to the undersigned, is filed before the mailing date of a first Office Action on the merits, or before a first office action after filing a Request for Continued Examination under §1.114.

(d) ☐ is filed after the first office action and more than three months after the application's filing date or PCT national stage date of entry filing but, as far as is known to the undersigned, prior to the mailing date of either a final rejection or a notice of allowance, whichever occurs first, and is accompanied by either the fee

($180) set forth in 37 CFR § 1.17(p) or a certification as specified in 37 CFR § 1.97(e), as checked below.

(e) ☐ is filed after the mailing date of either a final rejection or a notice of allowance, whichever occurred first, and the Issue Fee has not been paid, and is accompanied by the fee ($130) set forth in 37 CFR § 1.17(i)(1) and a certification as specified in 37 CFR § 1.97(e), as checked below. This document is to be considered as a petition requesting consideration of the information disclosure statement.

[If either of boxes (d) or (e) is checked above, the following "certification" under 37 CFR § 1.97(e) may need to be completed.] The undersigned certifies that:

(f) ☐ Each item of information contained in the information disclosure statement was cited in a communication mailed from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this information disclosure statement.

(g) ☐ No item of information contained in this information disclosure statement was cited in a communication mailed from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned after making reasonable inquiry, was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this information disclosure statement.

A list of the patent(s) or publication(s) is set forth on the attached Form PTO-1449 (Modified).

A copy of the items on PTO-1449 (Modified) is supplied herewith, except as noted below.

Those patent(s) or publication(s) which are marked with an asterisk (*) in the attached form PTO-1449 (Modified) are not supplied because they are (a) either U.S. Patents and this an application filed after June 30, 2003, or (b) were previously cited by or submitted to the Office in a prior application no. 10/349,262, filed January 22, 2003, and application no. 09/542,724, filed April 4, 2000, and relied upon in this application for an earlier filing date under 35 U.S.C. § 120.

A concise explanation of relevance of the items listed on form PTO-1449 (Modified) is:

(k) ☒ not given

(l) ☐ given for each listed item

(m) ☐ given for only non-English language listed item(s) [Required]

(n) ☐ is in the form of an English language copy of a Search Report from a foreign patent office, issued in a counterpart application, which refers to the relevant portions of the references [copy attached].

The Examiner is reminded that a "concise explanation of the relevance" of the submitted items "may be nothing more than identification of the particular figure or paragraph of the patent or publication which has some relation to the claimed invention," MPEP § 609.

While the information and references disclosed in this Information Disclosure Statement may be "material" pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR § 1.56(a) exists. It is submitted that the Information Disclosure Statement is in compliance with 37 CFR § 1.98 and MPEP § 609 and the Examiner is respectfully requested to consider the listed references.

Respectfully submitted,

STALLMAN & POLLOCK LLP

Dated: March 2, 2004

By: _____

Brian J. Keating
Reg. No. 39,520

Attorneys for Applicant(s)

INFORMATION DISCLOSURE CITATION *(Use several sheets if necessary)*	Docket Number (Optional) TWI-11120	Application Number NEW
	Applicant(s) John J. Sidorowich	
	Filing Date HEREWITH	Group Art Unit Unknown

U.S. PATENT DOCUMENTS

*Examiner Initial	Ref	Document Number	Date	Name	Class	Subclass	Filing Date
	*AA	4,999,509	03/12/1991	Wada et al.	250	559.27	03/26/1990
	*AB	5,148,513	09/15/1992	Koza et al.	706	13	09/18/1990
	*AC	5,222,192	06/22/1993	Shaefer	706	13	09/03/1992
	*AD	5,249,259	09/28/1993	Harvey	706	13	05/28/1992
	*AE	5,255,345	10/19/1993	Shaefer	706	13	09/01/1992
	*AF	5,343,554	08/30/1994	Koza et al.	706	13	05/11/1992
	*AG	5,394,509	02/28/1995	Winston	706	13	03/31/1992
	*AH	5,434,796	07/18/1995	Weininger	703	12	06/30/1993
	*AI	5,493,401	02/20/1996	Horie et al.	356	632	09/20/1994
	*AJ	5,541,848	07/30/1996	McCormack	700	213	12/15/1994
	*AK	5,568,590	10/22/1996	Tolson	706	13	12/17/1993
	*AL	5,581,657	12/03/1996	Lyon	706	13	07/29/1994
	*AM	5,586,218	12/17/1996	Allen	706	12	08/24/1995
	*AN	5,651,099	07/22/1997	Konsella	706	13	01/26/1995
	*AO	5,694,474	12/02/1997	Ngo et al.	381	66	09/18/1995
	*AP	5,864,633	01/26/1999	Opsal et al.	382	141	05/17/1996
	*AQ	5,896,294	04/20/1999	Chow et al.	700	121	03/11/1997
	*AR	5,926,773	07/20/1999	Wagner	702	22	10/27/1997
	*AS	5,953,446	09/14/1999	Opsal et al.	382	141	10/09/1998

FOREIGN PATENT DOCUMENTS

	Ref	Document Number	Date	Country	Class	Subclass	Translation Yes	Translation No

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

	*AT	R.A. Sequeira et al., "Automating the parameterization of mathematical models using genetic algorithms," *Computer and Electronics in Agriculture*, 1994, Vol. 11, pp. 265-290.
	*AU	E. Michielssen et al., "Optimal multilayer filter design using real coded genetic algorithms, " *IEE Proceedings-J*, Dec. 1992, Vol. 139, No. 6, pp. 413-420.
	*AV	T. Eisenhammer et al., "Optimization of interference filters with genetic algorithms applied to silver-based heat mirrors," *Applied Optics*, Nov. 1, 1993, Vol. 32, No. 31, pp. 6310-6315.
	*AW	S. Martin et al., "Simulated Darwinian evolution of homogeneous multilayer systems: a new method for optical coatings design," *Optics Communications*, Sep. 1, 1994, Vol. 110, No. 5/6, pp. 503-506.
	*AX	K. Rabinovitch et al., "Genetic algorithm and thin-film design," *Proceedings SPIE*, July 1994, Vol. 2262, pp. 163-174.
	*AY	S. Martin et al., "Synthesis of optical multilayer systems using genetic algorithms," *Applied Optics*, May 1, 1995, Vol. 34, No. 13, pp. 2247-2254.
	*AZ	T. Bäck et al., "Evolution Strategies for Mixed-Integer Optimization of Optical Multilayer Systems," *Proceedings Fourth Annual Conference on Evolutionary Programming*, 1995, pp. 33-51.
	*BA	D.J. Mikulin et al., "Fitting reflectivity data from liquid crystal cells using genetic algorithms," *Liquid Crystals*, 1997, Vol. 22, No. 3, pp. 301-307.
	*BB	M. Mitchell, "Genetic Algorithms: An Overview," *Complexity*, 1995, Vol. 1, No. 1, pp. 31-39.

Examiner	Date Considered
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

INFORMATION DISCLOSURE CITATION *(Use several sheets if necessary)*	Docket Number (Optional) TWI-11110	Application Number NEW
	Applicant(s) John J. Sidorowich	
	Filing Date HEREWITH	Group Art Unit Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	*BC	6,532,076	03/11/2003	Sidorowich	356	630	04/04/2000

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

	*BD	J.R. Koza, "Introduction to Genetic Algorithms," from *Genetic Programming*, Chapter 3, pp. 17-22 and 29.
	*BE	J.H. Holland, "Genetic Algorithms," *Scientific American*, July 1992, pp. 66-72.
	*BF	R.L. Riolo, "Survival of the Fittest Bits," *Scientific American*, July 1992, pp. 114-116.
	*BG	J.T. Fanton et al., "Multiparameter measurements of thin films using beam-profile reflectometry," *J. Appl. Phys.*, 1 June 1993, Vol. 73, No. 11, pp. 7035-7040.
	*BH	J.M. Leng et al., "Simultaneous measurement of six layers in a silicon on insulator film stack using spectrophotometry and beam profile reflectometry," *J. Appl. Phys.*, 15 April 1997, Vol. 81, No. 8, pp. 3570-3578.
	*BI	E.A. Rietman et al., "A Genetic Algorithm for Low Variance Control in Semiconductor Device Manufacturing: Some Early Results," *IEEE Transactions on Semiconductor Manufacturing*, May 1996, Vol. 9, No. 2, pp. 223-229.
	*BJ	J.F. Tang et al., "Automatic design and optical thin-film systems—merit function and numerical optimization method," *J. Opt. Soc. Am.*, Nov. 1982, Vol. 72, No. 11, pp. 1522-1528.

Examiner	Date Considered
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	